

Amendments to the Claims:

This listing of claims will replace all prior versions and listings of claims in the application:

- 1 1. (Currently Amended) A method for controlling a gap in an electrically conducting solid state structure, comprising the steps of:
 - 3 providing a plurality of an electrically conducting features disposed on a membrane including solid state structure an aperture aligned with a gap between the features in the structure;
 - 6 exposing the features structure to a fabrication process environment conditions of which are selected to alter an extent of the gap in the structure;
 - 8 applying a voltage bias across the gap in the structure during process environment exposure of the features structure;
 - 10 measuring electron tunneling current across the gap during process environment exposure of the features structure to indicate an extent of the gap; and
 - 13 controlling halting the process environment during process environment exposure of the features structure, based on the tunneling current measurement, to control an extent of the gap.

- 1 2. Canceled.

- 1 3. (Original) The method of claim 1 wherein controlling the process environment comprises comparing tunneling current measurement

3 with a threshold tunneling current corresponding to a prespecified gap extent
4 and controlling the process environment based on the comparison.

1 4. (Currently Amended) The method of claim 1 wherein the
2 conditions of the fabrication process environment are selected to increase an
3 extent of the ~~gap-in the structure~~.

1 5. (Currently Amended) The method of claim 1 wherein the
2 conditions of the fabrication process environment are selected to decrease an
3 extent of the ~~gap-in the structure~~.

1 6. (Currently Amended) The method of claim 1 wherein the
2 fabrication process environment comprises ion beam exposure of the features
3 structure.

1 7. (Currently Amended) The method of claim 6 wherein the ion
2 beam exposure comprises blanket ion beam exposure of the features
3 structure.

1 8. (Original) The method of claim 6 wherein the ion beam
2 exposure comprises rastering of the structure by a focused ion beam.

1 9. (Currently Amended) The method of claim 1 wherein the
2 plurality of electrically conducting features on the membrane structure
3 comprises two electrically conducting electrodes having the gap between the
4 electrodes.

1 10. (Original) The method of claim 9 wherein the electrically
2 conducting electrodes are disposed on an electrically insulating membrane
3 including an aperture aligned with the gap between the electrodes.

11. Canceled.

12. (Canceled)

13. (Canceled)

14. (Canceled)

15. (Canceled)

16. (Canceled)

17. (Canceled)

18. (Canceled)

19. (Canceled)

20. (Canceled)

21. (Canceled)

1 22. (Currently Amended) The method of claim 1 wherein the
2 fabrication process environment comprises electron beam exposure of the
3 | features structure.

1 23. (Previously Presented) The method of claim 9 wherein each
2 electrically conducting electrode is connected in a closed-loop circuit across the
3 gap for measuring electron tunneling across the gap.

1 24. (Previously Presented) The method of claim 9 wherein each
2 electrically conducting electrode is disposed in a connection to an electrical
3 contact pad.

1 25. (Previously Presented) The method of claim 24 wherein applying
2 a voltage bias across the gap in the structure comprises applying a voltage bias
3 between the electrical contact pads.

1 26. (Currently Amended) The method of claim 1 wherein providing
2 a plurality of an electrically conducting features disposed on a membrane solid
3 state structure including an aperture aligned with a gap between the features in
4 the structure comprises:

5 first providing an electrically conducting feature, disposed on a membrane
6 including an aperture, solid state structure without a gap; and
7 initiating the fabrication process environment to define the plurality of
8 electrically conducting features by forming provide a gap between the features in
9 alignment with the aperture in the solid state structure.

1 27. (Currently Amended) The method of claim 1 wherein providing
2 a plurality of an electrically conducting features disposed on a membrane solid
3 state structure including an aperture aligned with a gap between the features in
4 the structure comprises:

5 first providing an electrically conducting feature, disposed on a membrane
6 including an aperture, solid state structure without a gap; and
7 initiating a fabrication process environment to provide a gap in the
8 electrically conducting feature, in alignment with the aperture, solid state
9 structure that defines two electrically conducting electrodes separated from each
10 other by the gap.

1 28. (Previously Presented) The method of claim 27 wherein the
2 exposure of the structure to fabrication process environment increases the extent
3 of the gap between the two electrically conducting electrodes.

1 29. (Previously Presented) The method of claim 10 wherein the
2 electrically insulating membrane comprises a silicon nitride membrane.

1 30. (Currently Amended) The method of claim 11 wherein the
2 membrane is supported at its edges by a substrate comprises a silicon substrate.

1 31. (Previously Presented) The method of claim 1 wherein measuring
2 electron tunneling current comprises amplifying acquired electron tunneling
3 current prior to measuring electron tunneling current.

1 32. (Previously Presented) The method of claim 1 wherein measuring
2 electron tunneling current comprises digitizing acquired electron tunneling
3 current prior to measuring electron tunneling current.

1 33. (Currently Amended) The method of claim 1 wherein applying a
2 voltage bias across the gap comprises applying across the gap a voltage that is
3 less than a work function that is characteristic of the electrically conducting
4 features solid state structure.

1 34. (Currently Amended) The method of claim 1 wherein controlling
2 the process environment based on tunneling current measurement comprises:
3 determining an extent of the gap, g , as a function of measured tunneling
4 current, I , and applied voltage bias, V , as:

$$I(V) = aV^2 e^{-b/V}$$

$$2 \quad \text{where} \quad a = \frac{\sigma e^3}{16\pi^2 \phi \hbar g^2} \quad \text{and} \quad b = \frac{4(2m_e)^{1/2} \phi^{3/2} g}{3\hbar e}$$

3 and where σ is an area of each electrically conducting feature ~~the solid state~~
4 structure at opposite sides of the gap, e is the elementary charge, 1.6×10^{-19} C; \hbar
5 $= 1.1 \times 10^{-34}$ J·s; $m_e = 9.1 \times 10^{-31}$ Kg; and ϕ is a work function of the electrically
6 conducting features ~~solid state structure~~ at the gap; and
7 controlling the process environment based on the determined gap.

1 35. (Currently Amended) The method of claim 1 wherein controlling
2 the process environment based on tunneling current measurement comprises:
3 determining an extent of the gap, g , as a function of measured tunneling
4 current, I , and applied voltage bias, V , as:

$$I(V) = I_0 e^{-\alpha \sqrt{\phi} g}$$

$$6 \quad \text{where} \quad I_0 = \frac{\sigma e^2}{4\pi^2 \hbar^2} \frac{\sqrt{2m_e \phi}}{g} V \quad \text{and} \quad \alpha = \frac{2\sqrt{2m_e}}{\hbar}$$

7 and where σ is an area of each electrically conducting feature the solid-state
8 structure at opposite sides of the gap, e is the elementary charge, 1.6×10^{-19} C; \hbar
9 $= 1.1 \times 10^{-34}$ J·s; $m_e = 9.1 \times 10^{-31}$ Kg; and ϕ is a work function of the electrically
10 conducting features solid-state structure at the gap; and
11 controlling the process environment based on the determined gap.